## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 4575

Akihisa HONGO et al. : Attorney Docket No. 2006 0835A

Serial No. 10/581,669 : Group Art Unit 3723

Filed June 5, 2006 : Examiner Eileen P. Morgan

POLISHING APPARATUS AND

SUBSTRATE PROCESSING APPARATUS

## RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of June 23, 2009, Applicants hereby elect the invention of Group II, claims 11-16, without traverse, for further prosecution. In view of this election, a full examination on the merits of the present application is respectfully requested.

If there are any issues that the Examiner feels may best be resolved through a personal or telephone interview, the Examiner is kindly requested to contact the undersigned at the telephone number listed below.

The Commissioner is authorized to charge any deficiency or to credit any overpayment associated with this communication to Deposit Account No. 23-0975, with the EXCEPTION of deficiencies in fees for multiple dependent claims in new applications.

Respectfully submitted,

Akihisa HONGO et al.

/Jeffrey J. Howell/ By: 2009.07.23 10:36:41 -04'00'

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